■ Public Beamlines

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
1	**BL01B1 : XAFS I**	Wide energy range (3.8-113 keV), XAFS of dilute systems and thin films, Time-resolved XAFS by quick scan (time-resolved QXAFS), Depth-resolved XAFS, XAFS at low and high temperatures, Simultaneous XAFS and XRD measurements, Simultaneous XAFS and IR measurements
	XAFS measurement system, Ionization chambers, Lytle detector, 19-element Ge solid-state detector, Conversion electron yield (CEY) detector, Two-dimensional X-ray detector PILATUS, Electric furnace (1000 ℃), Cryostat (4 K), Gas supply and detoxifying system, Fourier transform infrared (FT-IR) spectrometer ($4000cm^{-1}$∼$500cm^{-1}$), Bending magnet (3.8-113 keV)	
2	**BL02B1 : Single Crystal Structural Analysis**	Charge density study using high energy X-ray, In-situ single crystal experiments, Micro crystal structure analysis
	Hybrid photon counting detector, Large cylindrical imaging plate camera. (Please contact the beamline scientist, if you submit the beamline proposal for the first time and want to use own experimental devices.) Bending magnet (8-115 keV)	
3	**BL02B2 : Powder Diffraction**	Charge density study from powder diffraction, Structural phase transition, *Ab initio* structure determination from powder diffraction, Crystal structure refinement by Rietveld method, In situ powder diffraction experiment under gas and vapor adsorption/desorption
	Automatic powder diffraction experiment (50 samples : 90 - 1100 K). Diffractometer for powder diffraction with MYTHEN micro-strip x-ray detector, Large Debye-Scherrer camera with imaging plate. Please contact to the responsible beamline scientist, if you want to do extremely low-temperature using cryostat (< 100 K), high temperature using furnace (<1300 K, Heating stage< 1647K), and In situ powder X-ray diffraction experiment under gas and vapor adsorption/desorption. Bending magnet (12-37 keV)	
4	**BL04B1 : High Temperature and High Pressure Research**	X-ray diffraction measurements and radiography under extreme conditions using large-volume press
	Large-volume press (SPEED-1500, SPEED-Mk.II), AC/DC power supply for resistance heating, Energy-dispersive X-ray diffractometer, 2D X-ray CCD detector, High-speed CCD camera, Ultrasonic velocity measurement system, Bending magnet [white, 20-150 keV; Si(111), 30-60 keV]	
5	**BL04B2 : High Energy X-ray Diffraction**	Structural analysis of glass, liquid, and amorphous materials
	X-ray PDF diffractometer and area flat panel detector for amorphous materials (Cryostat (20 K-RT), high-temperature furnace (~1,300 K), Aerodynamic levitation system (1,200~3,200 K)) Bending magnet [Si(511) 113 keV; Si(220), 61.4 keV]	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
6	**BL08W : High Energy Inelastic Scattering**	Magnetic Compton scattering, High-resolution Compton scattering, Compton scattering imaging, High-energy X-ray scattering, High-energy X-ray fluorescence analysis (XRF), Time-resolved pair distribution function analysis (PDF)
	Magnetic Compton scattering spectrometer, High-resolution Compton scattering spectrometer, High-energy X-ray fluorescence spectrometer, Flat area panel detector, Elliptical multipole wiggler (Station A, 110-300 keV; Station B, 100-120 keV)	
7	**BL09XU : HAXPES I**	Resonant hard X-ray photoelectron spectroscopy(HAXPES), Polarization-dependent HAXPES using diamond phase retarder, Depth analysis of electron state, Materials science and applied materials science
	・In-vacuum undulator (4.9-100 keV) ・Double channel cut monochromator(DCCM): Si 220 x 2, Si 311 x 2 (hn=4.9-12 keV, Tunable photon energy) / CCM Si 333,444,555 (hn=6,8,10 keV, Fixed energy) ・Double X-ray phase reterdar: Polarization change (hn=5.9-9.5 keV) ・Experimental hutch 1: High-energy-resolution photoelectron spectroscopy by hard X-ray excitation ・Experimental hutch 2: Depth analysis of in-solid and interface electron states ・Spot size: 1.5 μm(V)×20 μm(H) (EH1), 1.5 μm(V)×11 μm(H) / 1.5 μm(V)×1 μm(H)* (EH2) (* Users who wish to use the Φ1 μm focusing and/or mapping of photoelectron should contact the Beamline Scientist before applying for beamtime.) ・Temperature range of sample: ~20-400 K (Liquid He flow is used for cooling)	
8	**BL10XU : High Pressure Research**	Crystal structure analysis under high pressure using diamond-anvil cells, in-situ/operando observation of phase transition and compression behavior under extreme conditions, Material sciences under extreme conditions, High pressure Earth and planetary science
	・Systems for high pressure experiments using diamond anvil cells (<500 GPa) : X-ray flat panel detector, Imaging plate, photon-counting pixel detector with CdTe sensor, Ionization chamber, PIN PD, X-ray focusing lens, Multi-channel collimator, Raman spectroscopy system, pressure measurement system for ruby fluorescence method, Cryostat for high pressure experiment (7-300 K), Laser heating system (1,500-6,000 K), Gas pressure controller for gas membrane DACs (Please contact to BL scientists about using high speed photon-counting detector and/or Multi-channel collimator system before application.) ・In-vacuum undulator and Si (111)/ Si (220) double crystals: 6-61 keV ・Typical focused X-ray beam size: ~20 μm(H, V) (EH1)、0.8 μm(V)× 0.9 μm(H) / 1.8 μm(V)×2 μm(H) / 7 μm(V)×9 μm(H) (EH2)	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
9	**BL13XU : X-ray Diffractions and Scattering I**	X-ray diffraction and reflectivity measurements, Atomic-scale structural analysis of crystal surfaces and interfaces, ultrathin films, and nanostructures, Residual stress measurement, Time-resolved X-ray diffraction, In-situ process observation using X-ray diffraction, Operando X-ray diffraction, High-resolution powder X-ray diffraction and X-ray total scattering, Structural refinement using Rietveld analysis, In-situ/operando powder X-ray diffraction, Time-resoluved powder X-ray diffraction, Analysis of local structures using nanodiffraction
	Experimental hutch 1: Versatile Six-axis Diffractometer Experimental hutch 2: Diffraction measurement multi-purpose frame Experimental hutch 3: High-resolution powder X-ray diffraction Experimental hutch 4: Nanobeam X-ray diffraction system Si 111/ 311 double-crystal monochromator Experimental hutch 1: 6-axis X-ray diffractometer (HUBER), XYZ and swivel stage for sample, Double slit, Soller slit, Analyzer crystal, Sample heating stages(DHS1100, ADC XRD 1500 (Anton Paar)), Various ample atmosphare(Vacuum, N2, He, Al) Si PIN photodiode, Scintillation detector, SDD, Imaging plate, Ion chamber, 1D detector (6 consecutive MYTHEN), 2D detector (PILATUS) Experimental hutch 2: Sample stage with a hexapod, Robot arm for a detector, 2D detector (PILATUS X 300K, PILATUS X 2M) Experimental hutch 3: Powder Diffractometer equiped with six 2D CdTe photon-counting pixel detectors (Lambda 750 K) , Large Area Flat panel detector (XRD1611, 400 x 400 mm^2)、Sample Changer / Automatic measurement system (100 sample, 100～1100 K), Large area load table for various operand measurements(θ, XYZ) , low- or high-temperature N2 gas streams devices(90-473 K, RT - 1100 K), Remote gas handling system for capillary, Please contact to the responsible beamline scientist, if you want to do extremely low-temperature using cryostat (4 - 300 K), high temperature using Anton Paar furnace and Linkam flat plate furnace(~1300 K, ~1700 K), and In situ powder X-ray diffraction experiment under gas and vapor atmosphere. Experimental hutch 4: Nanobeam X-ray diffraction system, Fresnel zone plate, X-ray compound refractive lenses, HyPix-3000, Ionization chamber, Pi PIN photodiode, Fluorescence detector In-vacuum undulator (5-72 keV)	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
10	**BL14B2 : XAFS II**	X-ray imaging, XAFS in a wide energy range (5-72 keV), XAFS of dilute systems and thin films, Time-resolved XAFS by quick scan (Time-resolved QXAFS)
	X-ray imaging camera, XAFS measurement system, Ionization chamber, 19-element Ge solid-state detector (SSD), 7-element SDD, Lytle detector, Conversion electron yield (CEY) detector, Cryostat (10 K-RT), High-temperature cell for transmission (RT-1,000 ℃), High-temperature cell for fluorescence (RT-800 ℃), Gas supply and exhaust system [Users who wish to use the system should contact the Beamline Scientist (Honma) before applying for beamtime.] Bending magnet (5-72 keV)	
11	**BL19B2 : X-ray Diffractions and Scattering II**	Residual stress measurement, Structural analysis of thin film, surface and interface, Powder X-ray diffraction, X-ray topography, Ultrasmall-angle X-ray scattering
	Versatile High-throughput diffractometer (powder diffractometer), 8-axis diffractometer for general diffraction experiment, Small-angle X-ray scattering (SAXS) camera with a camera length of 0.7 - 40 m. For powder diffraction and SAXS experiment, fully-automated sample changers are available.	
12	**BL20XU : Medical and Imaging II**	X-ray micro-/nano-imaging: micro-CT, nano-CT (15-37.7keV), refraction/phase contrast imaging, X-ray diffraction tomography (XRD-CT), microbeam/scanning x-ray microscope Research and development of X-ray optics and optical elements, coherent X-ray optics Ultra small-angle X-ray scattering (USAXS, 23keV)
	High-precision diffractometer for various types of imaging, Liquid-nitrogen-cooled Si(111) double-crystal monochromator (7.62-37.7 keV) or Si(220) double-crystal monochromator (~61 keV), Middle-length undulator beamline (245 m), Beam size: 1.4 mm(H) x 0.7 mm(V) at 1st experimental hutch and 4 mm(H) x 2 mm(V) at 2nd experimental hutch, High-resolution X-ray imaging detectors (resolution ~1μm), Large view field X-ray imaging / XRD detectors (maximum FOV 40mm, resolution 10-20μm), Imaging intensifier (Be window, 4-inch type), Grove box for preparing samples (dew point about -60 degrees. installed in the downstream hutch outside the storage ring building. Ar atmosphere is available and N2 atmosphere also can be used if necessary. Users who wish to use them should contact the Beamline scientist beforehand at least 2 weeks), Integrated measurement including micro-/nano-CTs, XRD and microbeam is available (prior consultation with beamline scientist required) USAXS (23keV, 3.6x10^-4 < q < 2.9x10^-3 [1/Å], for smaller q-value than 3.6x10^-4 prior consultation with beamline scientist required)	
13	**BL20B2 : Medical and Imaging II**	Micro-radiography, micro-angiography, micro-tomography, and refraction-contrast imaging are the mainly used techniques. BL20B2 is also applicable to small-animal experiments for medical research. Research and development of basic techniques for evaluation of optical devices and X-ray imaging
	General-purpose diffractometer, High-resolution image detector (resolution, ~10 μm), Large-area image detector (field of view, 12 cm square), Medium-length beamline (215 m), Maximum beam size [experimental hutches 2 and 3, 300 mm(H) × 15 mm(V); experimental hutch 1, 60 mm(H) × 4 mm(V)], Bending magnet (Standard monochromator: 8-113 keV, multilayer monochromator: 40keV, 110keV)	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
14	**BL25SU : Soft X-ray Spectroscopy of Solid**	Research on electron states by photoemission spectroscopy (PES), Research on electronic band structures by angle-resolved photoemission spectroscopy (ARPES), Study of magnetic states by magnetic circular dichroism (MCD) of soft X-ray absorption, Analysis of surface atomic arrangement by photoelectron diffraction (PED), Nano-spectroscopic analysis using low-energy/photoemission electron microscope (SPELEEM).
	A branch: Retarding field analyzer (RFA), Soft X-ray PES, Low-energy/photoemission electron microscope B branch: MCD measurement system, Twin helical undulator (In the end of 2022B term, the Nano-XMCD finished operation for public use.) (A branch, 0.12-2 keV; B branch, 0.2-2 keV) Contact the Beamline Scientist of BL25SU before applying for beamtime for cases (1)-(2) below. (1) When you use RFA (2) When you wish to carry out experiments using carry-in devices	
15	**BL27SU : Soft X-ray Photochemistry**	Soft X-ray photoabsorption spectroscopy of dilute samples in partial fluorescence yield mode, Surface and interface analysis using depth-resolved Soft X-ray photoabsorption spectroscopy, Soft X-ray photoabsorption spectroscopy under ambient atmospheric pressure, Spectroscopy using soft X-ray microbeam, Observation of electron state in solids by soft X-ray emission spectroscopy
	B branch: High-energy soft X-ray beam (2.1-3.3 keV) using Si(111) crystal monochromator -Soft X-ray photoabsorption spectrometer (electron yield mode and partial fluorescence yield mode) -X-ray fluorescence analyzer -Scanning soft X-ray microspectroscopy C Branch: Low-energy soft X-ray beam (0.17-2.2 keV) using grating monochromator -Soft X-ray photoabsorption spectrometer (electron yield mode and partial fluorescence yield mode) -Soft X-ray photoabsorption spectroscopy under ambient atmospheric pressure (Users who wish to use the system should contact the Beamline Scientist (Nitta) before applying for beamtime.) - Soft X-ray emission spectrometer	
16	**BL28B2 : White Beam X-ray Diffraction**	White X-ray diffraction: X-ray topography, Energy-dispersive strain measurement High energy (~200 keV) X-ray microtomography High-speed X-ray imaging
	White X-ray topography system, Energy-dispersive XAFS system, Experimental system for biomedical application experiments, Multipurpose Bending magnet (White, ≥5 keV) Beam size: 50 mm(H) x 5 mm(V) @white beam, 50 mm(H) x 1.5 mm(V) @200keV	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
17	**BL35XU : Inelastic and Nuclear Resonant Scattering**	Phonons in solids and atomic dynamics in disordered materials by inelastic X-ray scattering. Atomic and molecular dynamics by nuclear resonant inelastic scattering and quasi-elastic scattering. Synchrotron-radiation-based Mössbauer spectroscopy. Nuclear excitation.
	Inelastic X-ray Scattering (IXS) (~1 to 100 nm^{-1}, 12 analyzers) ・ In-vacuum undulator (17.794 and 21.747 keV, Resolution: 3.0 and 1.5 meV) ・Spot size: ~Φ80 μm (Φ20 μm with KB setup) Nuclear Resonant Scattering (NRS): Nuclear inelastic scattering spectrometer, Time-domain/Energy-domain Mössbauer spectrometer, Quasi-elastic scattering spectrometer using time domain interferometry In-vacuum undulator (14.4 - 27.8 keV, 43.0 - 100 keV) ・Spot size: ~50 (H) × 25 (V) μm at 14.4 keV	
18	**BL37XU : Trace Element Analysis**	X-ray microbeam/nano-beam spectrochemical analysis, X-ray spectroscopic imaging, Ultratrace-element analysis, High-energy X-ray fluorescence analysis Projection/scanning/imaging XAFS microscopy, High brightness XAFS, Coherent diffraction imaging XAFS microscopy
	XAFS measurement system, Scanning X-ray microscope, Imaging X-ray microscope, X-ray tomography system, Multipurpose diffractometer, X-ray fluorescence analyzer, Bend crystal Laue analyzer, X-ray shutter Ionization chamber, PIN photodiode, 1-element Ge solid-state detector, 7-element Si drift detector, Indirect conversion X-ray image detector (High speed CMOS camera), Flat-panel detector, 2D pixel array detector In-vacuum undulator, Liquid-nitrogen-cooled double-crystal monochromator (Si(111): 4.5~37.7 keV, Si(511): 12~113 keV), Higher harmonics rejection mirrors (Pt/Ru coated, bent flat mirror for horizontal forcusing) Beam size: 1 mm(H)×0.7 mm(V), 100 nm(H)×100 nm(V) (W.D. = 100 mm, 5~55 keV), 500 nm(H)×300 nm(V) (W.D. = 300 mm, 5~30 keV)	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
19	**BL39XU : Magnetic Materials**	X-ray magnetic circular dichroism (XMCD) spectroscopy and element-specific magnetometry (ESM), X-ray emission spectroscopy (XES) and its magnetic circular dichroism, XMCD magnetic imaging and local ESM using micro/nanobeam, XAFS microscopy and local ESM, XAFS and XMCD at high pressure, X-ray spectroscopy using variable X-ray polarization (horizontally/perpendicularly linear or circular)
	Diamond circular polarization element (X-ray phase retarder, operable at 5-23 keV) XMCD spectrometer + Magnetic field generator [electromagnet (3.5 T), superconducting magnet (7 T, 2 K)] 4-axis X-ray diffractometer (Huber 424 + 511.1)(*), X-ray emission spectrometer(incident X-rays: 4.92-19 keV, emission X-rays: 4.4-18 keV)(*,**) Cryogenic device [helium-flow cryostat (11-500 K), superconducting magnet (2-300 K), pulse-tube-type cryostat (4-300 K)(*)] High-pressure generator (DAC, atmospheric pressure-180 GPa at RT, atmospheric pressure-40 GPa at low temperature)(*) KB focusing mirror for high-pressure XMCD (beam size, 2(vertical) x 9(horizontal)μm; W.D.=400 mm; 5-9.5 keV)(*) KB focusing mirror for microscopic XMCD and XAFS (beam size, 100-300 nm; W.D.= 80 mm; 5-16 keV)(*) (*)Users who wish to use these devices should contact the Beamline Scientist before applying for beamtime. (**)Some energy ranges are not available.	
20	**BL40XU : High Flux**	Fast time-resolved X-ray diffraction and scattering experiments, X-ray photon correlation spectroscopy, X-ray fluorescence analysis, Microbeam X-ray diffraction and scattering experiments, Micro-crystallography
	Experimental hutch 1: X-ray shutters, Fast CMOS video camera (Orca-Flash 4.0 (Hamamatsu), FASTCAM Mini AX200(Photron), FASTCAM Experimental hutch 2**: Precision diffractometer, Zone-plate-focusing optics, femtosecond-laser system, EIGER 1M *Helical undulator (8-17 keV) *Beam size at sample: 250 μm (H) x 40 μm (V) *Flux: 10^15 photons/s (12 keV) *Quasi-monochromatic beams (Δλ/λ=2%) without the need of a monochromator **Please contact the beamline scientist, if you submit the beamline proposal for the first time and want to use own experimental devices.	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
21	**BL40B2 : SAXS BM**	Small-angle X-ray scattering (SAXS)
	Small-angle scattering camera [Vaccum path length, 250, 500, 1000, 1500, 2000, 3000, 4000, 6000(*) mm] Pixel array detector (Pilatus3S 2M, Pilatus100KS and Eiger2 S 500K Dectris Ltd., ModuPIX ADVACAM) Imaging plate ditector (R-AXIS VII(*), Rigaku Corporation) X-ray imaging intensifier(*) (XII, 4 inch window) By the imaging camera for XII, CCD (C4742-98, Hamamatsu Photonics K.K.) or CMOS(C11440-22C, Hamamatsu Photonics K.K.) can be selected. Flat-panel detector (C9728DK-10, Hamamatsu Photonics K.K., for wide angle) Switching mechanism system between SAXS and WAXS (SAXS: 1500, 2000, 3000, 4000mm for Pilatus2 S 2M; WAXS: 85-170mm for Eiger2 S Sample-environment equipment: Temperature control (HCS302 and TS62 Instec Inc., 10002L Linkam Sci., Mechanical characterisation system(*) Bending magnet (6.5-22 keV) (*)Users who wish to use these devices should contact the beamline scientist before applying for beamtime.	
22	**BL41XU : Macromolecular Crystallography I**	Macromolecular crystallography, Micro-crystallography,Ultra-high resolution structural analysis
	Diffractometer for macromolecular crystallography In-vacuum undulator (normal mode, 6.5-17.7 keV; *high-energy mode, 19-35 keV) Beam size (at sample position): 4(H) × 5(V) μm2 ~ 22(H) × 45(V) μm^2 (normal mode), 30 × 30 μm^2 ~ 300 × 300 μm^2 (high energy mode) Hybrid photon counting detector EIGER X 16M (normal mode), EIGER2 X CdTe 4M (high-energy mode) Cryo-cooler (N_2 gas, ≥100 K; He gas, ≥20 K) Peltier-cooled silicon drift detector SPring-8 precise automatic cryo-sample exchanger (SPACE) *Users who wish to use the high-energy mode should contact the Beamline Scientist before applying for beamtime. Public use of cryogenic transmission electron microscopes, EM01CT (CRYO ARM 300) and EM02CT(CRYO ARM 200), have started in 2021B as an ancillary facility. Please check the following Web-site before using the beamline. http://stbio.spring8.or.jp/index_en.php	
23	**BL43IR : Infrared Materials Science**	Infrared microspectroscopy
	Wavenumber range: 100-20,000 cm^{-1} High-spatial-resolution microscope: Objectives (x36(NA=0.5, WD=10 mm), x15(NA=0.4, WD=24 mm), x20(ATR)), Cryostat (4.2 K∼400 K), Long-working-distance microscope: Objective (x8(NA=0.5, WD=50 mm), Diamond anvil cell+Cryostat (0.4 mm culet/30 GPa, 10∼400 K), Cryostat Magneto-optical microscope: Objective (x16(NA=0.3, WD=40 mm), Magnetic field 14 T, Cryostat (4.2∼300 K)	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
24	**BL45XU : Macromolecular Crystallography II**	Macromolecular crystallography, Micro-crystallography, Automation & High throughput data collection for protein crystallography
	Diffractometer for macromolecular crystallography In-vacuum undulator (6.5-16.0 keV) Beam size (at sample position): 5(H) × 5(V) μm^2 ~ 50(H) × 50(V) μm^2 Hybrid photon counting detector PILATUS 6M Cryo-cooler (N_2 gas, ≥100 K) SPring-8 precise automatic cryo-sample exchanger (SPACE) Please check the following Web-site before using the beamline. http://stbio.spring8.or.jp/index_en.php	
25	**BL46XU : HAXPES II**	Hard X-ray photoemission spectroscopy
	In-vacuum undulator (5.5-37 keV) Hard X-ray photoemission spectroscopy system (Scienta Omicron R4000)	
26	**BL47XU : Micro-CT**	X-ray optics, Planetary science, Materials science, Applied materials science
	In-vacuum undulator (5.2-37.7 keV, horizontal polarization) High-spatial-resolution micro-tomography system, High speed imaging system, Hard X-ray microbeam/scanning microscopy experiment Please contact to beamline scientists before putting on a new proposal to BL47XU.	

■RIKEN Beamlines

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
27	**BL05XU : R&D-ID**	Strucutural analysis by small and wide angle X-ray scattering
	Photon energy: 7~15 keV Photon flux < 1×10^{13} photons/s (12.4 keV) Sample-to-detector distance: ~10 cm - 4 m For other conditions and facilities, contact the Beamline Scientist beforehand.	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
	BL17SU : RIKEN Coherent Soft X-ray Spectroscopy	>Scanning soft x-ray spectromicroscope --- A3 station Microspectroscopic observation of sample surface under conditions ranging from low >Versatile photoemission electron microscope --- Bc station Electronic/magnetic states imaging (resolving power: better than 100 nm) and its time-
28	Helical-8 undulator, Energy range for A and B branches (225* - 2,000 eV) (*225 eV for Circularly polarized light, 272 eV for Horizontally polarized light, 136 eV for Vertically polarized light) , Energy resolution (E/dE ~10,000), Beam size at sample position [~30 μm(H) × 4 μm(V)] Before applying for public use of BL17SU, contact the following persons in charge of respective equipment. Scanning soft x-ray spectromicroscope: Suga (hiroki-suga@spring8.or.jp) at JASRI/RIKEN, Oura at RIKEN (oura@spring8.or.jp) versatile photoemission electron microscope: Ohkochi (o-taku@spring8.or.jp) at JASRI/RIKEN Free space where users can bring their systems: Oura (oura@spring8.or.jp) at RIKEN	
	BL19LXU : RIKEN SR Physics	Research on physical science requiring ultrahigh-brilliance X-ray beam from long undulator
29	Experimental station/system: 5(W) × 3.4(D) × 4.5(H) m^3 open hutch, Optical bench, PIN photodiode, Scintillation counter, Ionization chamber, Stepping motor drivers and controllers, NIM Bin power supply, Counter, Trigger signal synchronized with RF of storage ring Light source (energy range at sample position, etc.): In-vacuum undulator (7.1-18 keV, 22-51 keV, flux of ~1014 photons/s at 12.4 keV) For other conditions and facilities, contact the Beamline Scientist beforehand.	
	BL26B1/B2 : RIKEN Structural Genomics I & II	Structural biology research based on single-crystal X-ray diffraction
30	Area detector [Dectris EIGER4M (BL26B1), Rayonix MX225HS (BL26B2)], Goniometer with horizontal spindle axis, Blowing cryo-cooler (95 K-RT), Sample changer SPACE, Bending magnet (6.5-15.5 keV) Please check the following Web-site before using the beamline. http://stbio.spring8.or.jp/index_en.php	
	BL29XU : RIKEN Coherent X-ray Optics	Research on physical science using long beamline and coherent X-ray beam
31	Experimental station/system: Open hutches with size of 5(W) × 3(D) × 3.3(H) m^3 [EH1], 10(W) × 4.25(D) × 4.5(H) m^3 [EH2], 8(W) × 4(D) × 3.3(H) m^3 [EH3], and 6(W) × 3(D) × 3.3(H) m^3 [EH4], Optical benches, PIN photodiodes, Scintillation counters, Ionization chambers, Stepping motor drivers and controllers, NIM Bin, Power supply, Counter, Visible-conversion X-ray camera, Trigger signal synchronized with RF of storage ring Light source (energy range at sample position, etc.): In-vacuum undulator (1st order harmonics : 5-19 keV, 3rd order harmonics : 15-56 keV, flux of ~6 × 10^{13} photons/s at 10 keV), silicon monochromator(111 plane)(4.4 ~ 37.8 keV) For other conditions and facilities, contact the Beamline Scientist beforehand.	

No.	Beamline name	Research areas
Experimental station/system Light source (energy range at sample position, etc.)		
32	**BL32XU : RIKEN Targeted Proteins**	Structural biology, X-ray crystallography for biopolymer, Micro-crystallography for ultrafine proteins
	Experimental station/system: EEM focusing mirror unit, Ultralow-eccentricity high-precision goniometer, Ultralow-temperature He blower, Hybrid photon counting detector (DECTRIS EIGER X 9M), Large-volume sample mounting robot with applicability to Hampton pins Light source (energy range at sample position, etc.): [Light source] Hybrid undulator [Beam size at sample position] 1×1-10×10 μm^2 [Flux of 1 μm beam] 7×10^{10} photons/s at 12.4 keV [Energy range] 9-18 keV (If you prefer to use lower energy X-ray than 9 keV, please contact us) Please check the following Web-site before using the beamline. http://stbio.spring8.or.jp/index_en.php	
33	**BL36XU : RIKEN Materials ScienceII**	Time-resolved QXAFS using tapered-Undulator beam
	[Energy region] 4.5-35 keV, [beam size] 40 μm(V)×500 μm(H), 100 nm(V)×100 nm(H), [time resolution] QXAFS(20 ms). [light source and optics] In-vacuum tapered undulator, channel-cut crystal monochromators (Si(111), Si(220)), Rh/Pt coated vertical/horizontal focusing mirrors, Rh/Pt coated KB mirrors(4.5-35 keV). [Measurement system] Transmission XAFS measurement system, 25-element Ge detector, 4-element SDD, PILATUS 300KW, 4-element Merlin detector, indirect X-ray image detector In BL36XU, only Quick XAFS apparatus is open for public use. When you apply for public use of BL36XU, please contact to the beamline staff	
34	**BL38B1 : RIKEN Structural Biology I**	Small Angle X-ray Scattering
	Bending Magnet(6.5～15.5 keV)　＊User opereation is only 12.4 keV or 15.5 keV.	
	Camera length; 300, 2500 mm Detector; DECTRIS PILATUS3X 2M. Temperature cotrollable solution cell (4～60℃) , HPLS system for SEC-SAXS	
	*Use only BioSAXS.	
35	**BL43LXU : RIKEN Quantum NanoDynamics**	meV Scale IXS for atomic dyanmics
	Energy: 14.4-26 keV (Fundamental), meV Spectrometer for atomic dynamics	
36	**BL44B2 : RIKEN Materials Science I**	Structural analysis of periodic and aperiodic systems by total scattering
	Wavelength: 0.41～0.8 Å Instrument: Two-axis powder diffractometer (2θ range: 0.5～153°, 2θstep: 0.01°) Temperature: -180～800℃	